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Substitute for form 1449A/PTD INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i>				Complete if Known	
				Application Number	Unknown
				Filing Date	Herewith
				First Named Inventor	Mark A. Lemkin
				Group Art Unit	Unknown
				Examiner Name	Unknown
				Attorney Docket Number	AIMI-01833US0
Sheet	1	of	5		

09/944395
08/31/01

U.S. PATENT DOCUMENTS						
Examiner Initials	Cite No. 1	U.S. Patent Document		Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	
		Number	Kind Code ² (if known)			
JF JF JF JF JF JF JF JF JF JF JF JF JF JF JF		4,861,420		Knutti et al.	08-29-1989	156/1633
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	5,504,026		Kung	04-02-1996	432/51	
	5,506,175		Zhang et al.	04-09-1996	437/229	

[illegible]

Examiner Signature	<i>[Signature]</i>	Date Considered	10/18/03
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INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)				Application Number	Unknown
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				Group Art Unit	Unknown
				Examiner Name	Unknown
Sheet	2	of	5	Attorney Docket Number	AIMI-01833USO

OTHER PRIOR ART – NON PATENT LITERATURE DOCUMENTS			
Examiner Initials ¹	Cite No. ²	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ³
[Signature]		GARY K. FEDDER and TAMAL MUKHERJEE, "Physical Design for Surface-Micromachined MEM Proceedings of the 5th ACMSIGDA Physical Design Workshop, 4/15-17/1996, pp. 53-60	
[Signature]		BERNHARD E. BOSER, "Electronics for Micromachined Inertial Sensor", 1997 Int'l Conference on Solid State Sensors and Actuators, Chicago, IL, pp. 1169-1172, June 16-19, 1997	
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[Signature]		CHANG LIU and Y. BAR-COHEN, "Scaling Laws of Microactuators and Potential Applications of Electroactive Polymers in MEMS", Proceedings of SPIE's 6th Annual Int'l Symposium on Smart Structures and Materials, 1-5 March, 1999, Newport Beach, CA, Paper No. 3669-33	
[Signature]		CRIST LU, MARK LEMKIN and BERNHARD E. BOSER, "A Monolithic Surface Micromachined Accelerometer with Digital Output", IEEE Journal of Solid-State Circuits, Vol. 30, No. 12, December 1995	
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[Signature]		LALITHA PARAMESWARAN, CHARLES H. HSU, MARTIN A. SCHMIDT, "IC Process Compatibility of Sealed Cavity Sensors", 1997 Int'l Conference on Solid-State Sensors and Actuators, Chicago, IL, pp. 625-628, June 16-19, 1997	
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[Signature]		JOHN H. COMTOIS, M. ADRIAN MICHALICEK, CAROLE CRAIG BARRON, "Fabricating Micro-Instruments in Surface-Micromachined Polycrystalline Silicon", Proceedings of the 43rd Int'l Instrumentation Symposium Instrument Society of America, 1997, pp. 169-179	

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